

Supporting Information (SI)

**Electric field tunable of the electronic properties
and contact types in MoS₂/SiH heterostructure**

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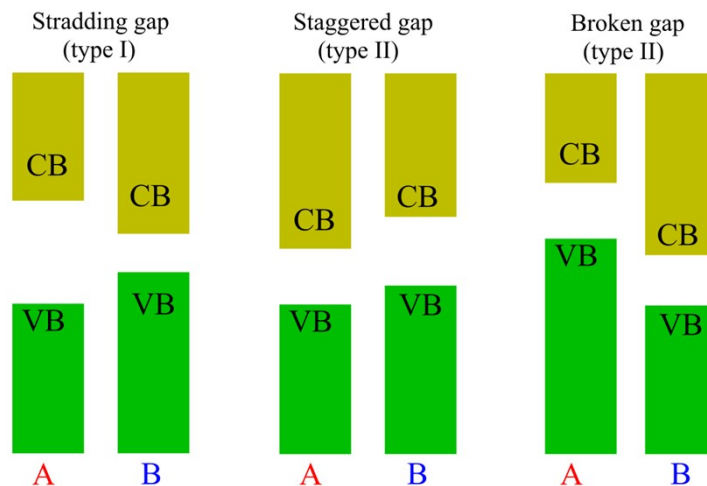


Fig. S1. Band alignments between two different semiconductors A and B.

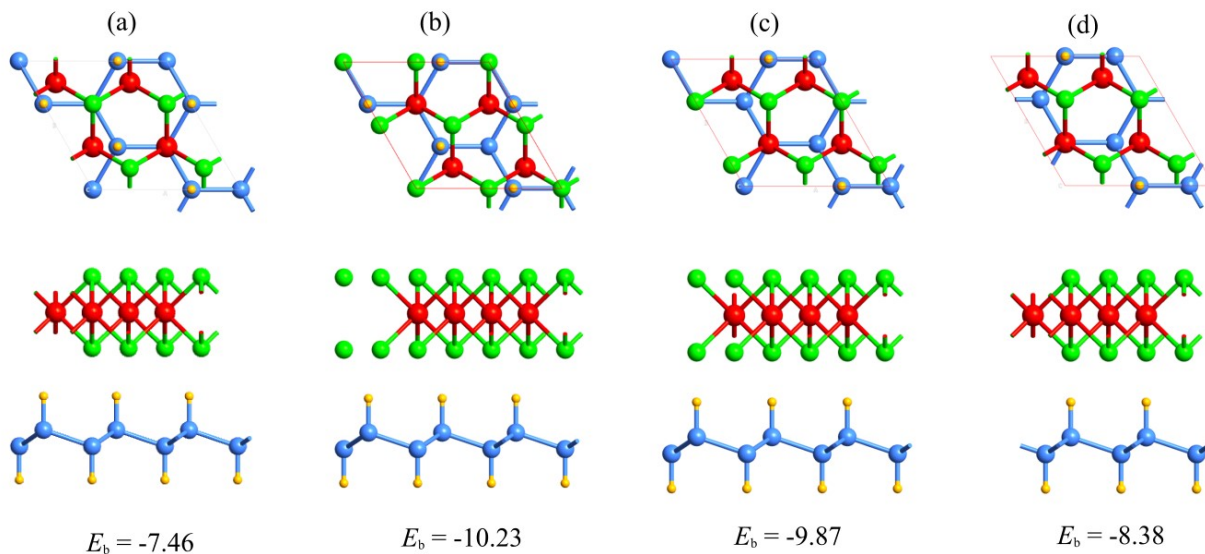


Fig. S2. Different stacking configurations of MoS2/SiH heterostructures (a) stacking I, (b) stacking II, (c) stacking III and (d) stacking IV.

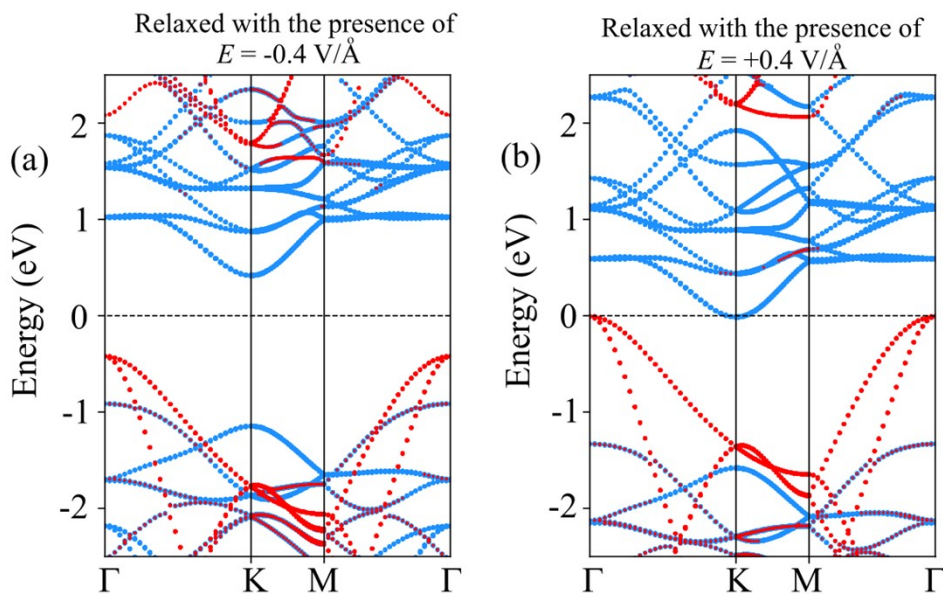


Fig. S3. Projected band structures of MoS2/SiH heterostructure under the applied strengths of electric field of (a) $E = -0.4 \text{ V/\AA}$ and (b) $E = +0.4 \text{ V/\AA}$. These values of electric field were applied for both the geometric optimization and electronic properties calculations.